Honeywell Sensing and Control

AWM43600V



Actual product appearance may vary.

Airflow Sensor, Signal Conditioning: Amplified; Flow/Pressure Range: + 6.0 SLPM; Port Style: Manifold

Features

- Precision silicon micromachining
- Sensitive to low flows 0.1 sccm to 20 SLPM
- Adaptable for use with higher flows
- Fast response time
- Analog output
- Low power consumption
- Repeatable response
- Laser trimmed interchangeability
- · Accurate, cost effective flow sensing
- In-line printed circuit board terminals
- Standard 2.54 mm (0.100 in) mounting centers
- \bullet Accurate sensing of low pressure 0.001 in to 4.0 in $\rm H_2O$ (0.003 to 10 mbar)

Potential Applications

- Damper control for heating, ventilation, and air conditioning systems
- Gas analyzers
- Low vacuum control
- Process control
- Medical respirators and ventilators
- Oxygen concentrators
- · Leak detection equipment
- Vent hoods
- Anesthesia control
- Gas metering
- Gas chromatography

Description

OPERATION

The microbridge mass airflow sensor operates on the theory of heat transfer. Mass airflow is directed across the surface of the sensing elements. Output voltage varies in proportion to the mass air or other gas flow through the inlet and outlet ports of the package. The specially designed housing precisely directs and controls the airflow across the microstructure sensing element. Mechanical design of the package allows it to be easily mounted to printed circuit boards. The microbridge mass airflow sensor has a unique silicon chip based on advanced microstructure technology. It consists of a thin-film, thermally isolated bridge structure containing heater and temperature sensing elements. The bridge structure provides a sensitive and fast response to the flow of air or other gas over the chip. Dual sensing elements positioned on both sides of a central heating element indicate flow direction as well as flow rate. Laser trimmed thick film and thin film resistors provide consistent interchangeability from one device to the next.

The microbridge mass airflow sensor uses temperature sensitive resistors deposited within a thin film of silicon nitride. They are suspended in the form of two bridges over an etched cavity in the silicon. The chip is located in a precisely dimensioned airflow channel to provide a repeatable flow response. Highly effective thermal isolation for the heater and sensing resistors is attained by etching the cavity space beneath the flow sensor bridges. The small size and thermal isolation of the microbridge mass airflow sensor are responsible for the extremely fast response and high sensitivity to flows.

Dual Wheatstone bridges control airflow measurement -- one provides closed loop heater control, the other contains the dual sensing elements. The heater circuit minimizes shift due to ambient temperature changes by providing an output proportional to mass flow. The circuit keeps the heater temperature at a constant differential (160 °C) above ambient air temperature which is sensed by a heat-sunk resistor on the chip. The ratiometric voltage output of the device corresponds

to the differential voltage across the Wheatstone bridge circuit.

NOTICE

The effects of dust contamination, which may result form some applications, can be minimized. By design, dust particles that may be present in the air stream will flow past the chip parallel to the chip surface. In addition, the microstructure chip produces a thermophoretic effect, which repels micrometer sized dust particles away from the bridge structure.

A simple filter will prevent dust adherence to chip edges and channel surfaces. Adequate filtering in most applications can be achieved with a disposable five-micron filter used in series on the upstream side of the airflow device.

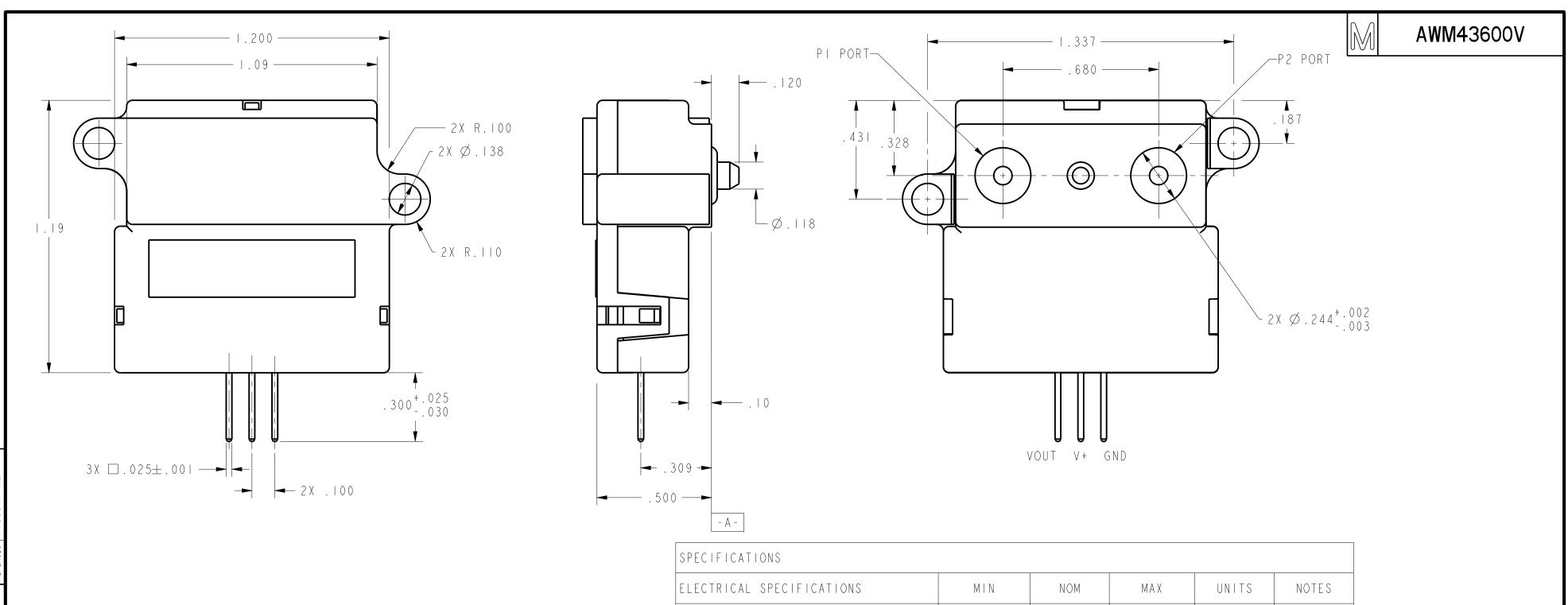
CAUTION

PRODUCT DAMAGE

 $\label{lem:awm} \mbox{AWM Series Microbridge Mass Airflow Sensors are not designed to sense liquid flow and will be damaged by liquid flow through the sensor.}$

Failure to comply with these instructions could result in product damage.

Product Specifications						
Signal Conditioning	Amplified					
Flow/Pressure Range	6.0 SLPM					
Output Voltage @ Trim Point	5.0 Vdc ±0.15 Vdc @ 6.0 SLPM					
Port Style	Manifold					
Series Name	AWM40000					
Null Shift over Temperature	±0.025 Vdc					
Output Shift over Temperature	±6 % Reading					
Maximum change in flow rate	5.0 SLPM/s					
Max. Repeatability & Hysteresis Error	±1% Reading					
Null Offset	1.0 Vdc ±0.05 Vdc					
Response Time	1 ms typ., 3 ms max.					
Supply Voltage	8.0 Vdc min., 10.0 Vdc typ., 15.0 Vdc max.					
Maximum Common Mode Pressure	25.0 psi					
Power Consumption	75 mW max.					
Operating Temperature Range	-25 °C to 85 °C [-13 °F to 185 °F]					
Storage Temperature Range	-40 °C to 90 °C [-40 °F to 194 °F]					
Media Compatibility	Dry gas only					
Weight	11 g					
Shock	100 g peak (5 drops, 6 axes)					
Availability	Global					
Comment	Nitrogen calibration gas					
UNSPSC Code	411121					
UNSPSC Commodity	411121 Transducers					



NOTES

NUMBER AWM43600V

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JLH 16SEP02 C 0032043 DDN 10JUL07

- I RESPONSE TIME IS TYPICALLY I msec FROM 10-90%
- 2 OUTPUT VOLTAGE IS RATIOMETRIC TO SUPPLY VOLTAGE
- 3 REPEATABILITY & HYSTERESIS TOLERANCES REFLECT INHERENT INACCURACIES OF THE MEASUREMENT EQUIPMENT
- 4 MOUNTING TORQUE 2 1/2 TO 6 IN.LBS (.3 TO .7 NEWTON METERS)
- 5 AN II VDC MIN SUPPLY VOLTAGE IS REQUIRED WITH TEMPERATURES ABOVE 50°C

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SPECIFICATIONS						
ELECTRICAL SPECIFICATIONS	MIN	NOM	MAX	UNITS	NOTES	
RECOMMENDED EXCITATION	9.990	10.000	10.010	Vdc		-
POWER SUPPLY (MIN/MAX)	10.000		15.000	Vdc	(2) (5)	
POWER CONSUMPTION			7.5	mW		
FLOW RANGE		0 - 6 LPM				
OUTPUT LOAD	IO mA	10 mA source 20 mA Typ				
CALIBRATION GAS		NITROGEN				
OUTPUT @ LASER TRIM POINT	5.0	5.000 VDC @ 6LPM				
NULL OUTPUT	1.0	1.000 ± .050 VDC				
NULL OUTPUT SHIFT:						
25 TO -25°C AND 25 TO 85°C			±50	m v d c		
FULL SCALE OUTPUT SHIFT:						_
+25°C TO -25°C			-7.0	% READ		_
+25°C TO +85°C (5)			7.0	% READ		-
RATIOMETRICITY ERROR			±0.8	% READ	(Typ) (2)	-
REPEATABILITY & HYSTERESIS			±1.0	% READ	(3)	-
RESPONSE TIME		1.0	3.0	msec	()	-
FLOW SPECIFICATIONS	FLOW (SLM)	NOMINAL (vdc)	TOLERANCE ±(vdc)			
	0	1.000	0.050			
		3.100	0.30			
	2	3.800	0.30			
	3	4.400	0.35			
	4	4.700	0.25			_
	5	4.890	0.20			_
	6	5.000	0.150			_
MECHANICAL SPECIFICATION S			SPECIFICATION LIMITS			
PRESSURE DROP @ FULL SCALE TEMPERATURE RANGE		8 IN. H20 Typ				
OPERATING (5)		-25 TO +85°C				THIRD ANGLE PROJECTION
STORAGE		-40 TO + 125°				⊕ – <u></u> =-
TERMINATION	MINATION (.100" CENTERS) .025			5" SQUARE		SCALE 3:1
SHOCK RATING (5 DROPS, EACH OF 6 AXIS) 100g PEAK					DO NOT SCALE PRINT	
OVERPRESSURE 25 PSI						UNLESS OTHERWISE SPECIFIED TOLERANCES ARE
THIS DRAWING COVERS A PROPRIETARY ITEM AND IS THE PROPERTY OF MICRO SWITCH. A DIVISION OF HONEYWELL. THIS DRAWING IS NOT TO BE COPIED OR USED WITHOUT THE APPROVAL OF MICRO SWITCH.						ONE PLACE (.0) ± .030
HONEYWELL. THIS DRAWING IS NOT TO BE COPIED OR USED WITHOUT THE APPROVAL OF MICRO SWITCH. CATALOG LISTING					TWO PLACES (.00) ±.015	
MICRO SWITCH	GAS FLOW	TRANSD	JCER			THREE PLACES (.000) ± .005
a Honeywell Division SPECIFICATION		AWM43600V		ANGLES ±		
APPLIES FED. MFG. CODE 91929					WEIGHT	
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ANSI YI4.5M-1982